Requirements

Injection Chamber

UHV chamber with one DN40CF port for ALI (facing the sample), and another for a pressure gauge (as close as possible to the sample plane).

Pumping

- Injection chamber:
 Dry primary pump, S>5m³/h, p_{base}~10⁻²mbar.
 Turbomolecular pump, 250l/s<S<700l/s
- Pre-injection system:
 Dry pump w/ gas-ballast, S>5m³/h, p_{hase}<22mbar

Pressure Measurement

- Injection chamber:
 Pfeiffer PKR 261/251 (full range Pirani-Penning)
- Pre-injection system:
 Pfeiffer APR 250 (direct piezo gauge)

Carrier Gas

Carrier gas cylinder with double-stage pressure regulator. Argon, purity >99%, recommended.

Control PC

PC running Windows v. 7 and above (32 or 64 bit) Connection to control unit via USB.

Products

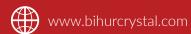
- ALI-DS001: ALI Deposition System
- ALI-SCU001: ALI Software & Control Unit Package
- ALI-PM001: ALI Preparation Module (Customizable)

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TECHNICAL SOLUTIONS AND EQUIPMENT FOR VACUUM AND ULTRA-HIGH VACUUM APPLICATIONS

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ATOMIC LAYER INJECTION

Deposition in UHV from solution



ALI-1000

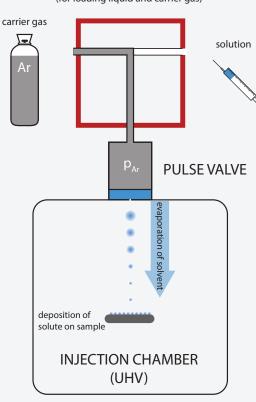
A UHV deposition system from solution for large or fragile molecules.

ALI uses a pulse valve to inject a small amount of the solution or colloidal suspension containing the material to be deposited.

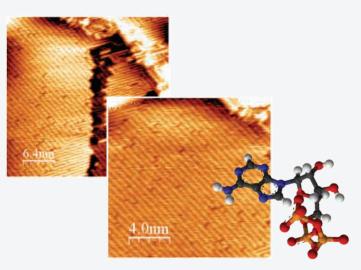
A pre-injection system holds the solution at a desired carrier-gas pressure.

When the solution is pulse injected, it forms a spray. The solute travels within the microdrops, as the solvent evaporates, and is finally deposited on the sample.

PRE-INJECTION SYSTEM (for loading liquid and carrier gas)

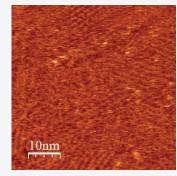


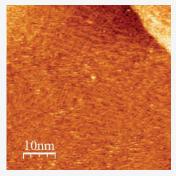
ATP on Cu(110)



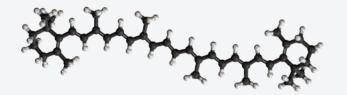
Courtesy of Jesús M. Sobrado Centro de Astrobiología (CSIC-INTA), Madrid, Spain

ß-Carotene on Au(111)





Courtesy of Franz Himpsel and Celia Rogero, NanoPhysics Lab, Centro de Física de Materiales (CSIC-UPV/EHU), Donostia-San Sebastián, Spain



ALI's Features

- Deposit macromolecules, nanoparticles, etc from solution
- Ideal for delicate molecules that degrade during evaporation or sublimation!



• Pulses down to 1ms

ALI-DS001



- User-friendly software interface
- Incorporates safety features to protect the vacuum system
- Also available:
 Customized preparation modules

